

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Shunpei Yamazaki et al.	Art Unit :	1792
Serial No. :	10/826,920	Examiner :	Karla A. Moore
Filed :	April 19, 2004	Conf. No. :	1020
Title :	AN APPARATUS FOR FORMING A FILM AND AN ELECTROLUMINESCENCE DEVICE		

Mail Stop Amendment

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO ACTION OF JUNE 27, 2008

Claims 1-3, 5-9, 11-15, 17-21, 23, 24 and 29-36 are now pending, of which claims 1, 7, 13 and 19 are independent. Claims 29-32 have been withdrawn from consideration.

Claims 1, 3, 6, 7, 9, 12, 13, 15, 18, 19, 21 and 24 have been rejected as being unpatentable over Yamazaki (U.S. Patent Application Publication No. 2001/0006827) in view of Peng (U.S. Patent No. 6,641,674) and Hirata (JP09-143697). Applicant requests reconsideration and withdrawal of this rejection because neither Yamazaki, Peng, Hirata, nor any proper combination of the three describes or suggests an installation chamber connected to a film formation chamber, where the installation chamber comprises means adapted to move a first evaporation source, means adapted to move a second evaporation source, and means adapted to move a third evaporation source, as recited in each of the independent claims.

The rejection provides no indication as to where the installation chamber may be found in Yamazaki, Peng or Hirata. In particular, while the rejection indicates that Yamazaki discloses a film forming apparatus that includes a load chamber (Figure 5, 504), a conveyance chamber (501) connected to the load chamber, and a film formation chamber (509 or 506) connected to the conveyance chamber, with the film formation chamber including a first evaporation source (Figures 2A and 2B, 212) and means for scanning an evaporation source across the width of a substrate, the rejection provides no indication as to where the installation chamber may be found.

Yamazaki states, in paragraph [0031], that a “structure of an evaporation chamber prepared in a film formation apparatus ... is shown in FIGS. 2A and 2B,” and, in paragraph [0037], that the “evaporation source 212 is scanned from one end of the substrate 203 to the

other end.” Yamazaki’s “evaporation chamber 201” best corresponds to “the film formation chamber” recited in the claims. Yamazaki indicates that the evaporation source 212 is located in the film formation chamber 201 (see FIGS. 2A and 2B).

Yamazaki does not describe an installation chamber that includes means adapted to move a first evaporation source, means adapted to move a second evaporation source, and means adapted to move a third evaporation source. In particular, while the claims recite that these three means to move evaporation sources are in the installation chamber, Yamazaki describes that a single means 212 adapted to move an evaporation source is located in the evaporation chamber 201, which, as noted above, best corresponds to the film formation chamber.

Peng and Hirata also fail to describe or suggest placing an evaporation source in an installation chamber.

Accordingly, for at least these reasons, the rejection should be withdrawn.

Claims 2, 5, 8, 11, 14, 17, 20, 23 and 29-36 have been rejected as being unpatentable over Yamazaki, Peng and Hirata in view of Yamamoto (U.S. Patent No. 6,179,923). Applicant requests reconsideration and withdrawal of this rejection because Yamamoto does not remedy the failure of Yamazaki, Peng and Hirata to describe or suggest the subject matter of the independent claims. While the rejection indicates that Yamamoto describes an installation chamber at col. 5, line 53 to col. 6, line 42, neither this passage nor any other passage of Yamamoto describe or suggests an installation chamber that contains means for moving evaporation sources, as recited in each of the independent claims.

Applicant submits that all claims are in condition for allowance.

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Attorney's Docket No.: 12732-0228001 / US7116

No fee is believed to be due. Please apply any charges or credits to deposit
account 06-1050.

Respectfully submitted,

Date: 9/29/08



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